

ABSTRACT

The present invention relates to a substrate processing apparatus for processing a substrate. The substrate processing apparatus (10) at least one first processing module (21a, 21b) configured to process a substrate W using a liquid; at least one second
5 processing module (31) configured to process the substrate W that has been processed by the first processing module (21a, 21b); a transfer robot (22) which is placed in a transfer area (28) for transferring the substrate W from the first processing module (21a, 21b) to the second processing module (31); a pair of gutters (53, 54) which are disposed above a floor (51) provided in the transfer area (28) and coupled to drain lines (58, 58); and at
10 least one inclined plate (56) which is hung over the pair of gutters (53, 54). An upper surface of the inclined plate (56) extends from one of the pair of gutters (53, 54) to the other at an angle with respect to a horizontal direction.

FIG. 2